



IFW

PATENT
Customer No. 22,852
Attorney Docket No. 3180.0342

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)	
)	
NOBUHIRO KOMINE)	
)	
Application No.: 10/721,903)	Group Art Unit: 2851
)	
Filed: November 26, 2003)	Examiner: D. Rutledge
)	
For: RETICLE, EXPOSURE)	Confirmation No.: 9102
MONITORING METHOD,)	
EXPOSURE METHOD AND)	
MANUFACTURING METHOD)	
FOR SEMICONDUCTOR DEVICE)	

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

AMENDMENT

In reply to the Office Action mailed November 16, 2005, the period for response to which extends through February 16, 2006, please amended the above-captioned application, as follows:

Amendments to the Claims are reflected in the listing of claims in this paper.

Remarks/Arguments follow the amendment section of this paper.